

*Easy & Safe Automatic Decapsulation*

# MIS Wet Etch

**Model No. DW-07**



### Main Function & Features

- Automatic decapsulation system : Etching & Cleaning
- Easy control system using micom controller
- Fast, dual heating process (Jig plate heating & IR beam heating)
- Accurate Decapsulation (Chemical etchant dispensing volume: minimum 0.005ml)
- Repetitions made simple using recipe files
- Safe operation (Decapping in chamber, Fume exhausting system)
- No need for consumable gaskets
- Minimal maintenance cost and long lifecycles

### Specification

Item	Description
Dimension	740(W) x 600(D) x 1650(H) mm
Weight	Approx. 180 kg
Procedure	Etching, Heating, Cleaning
Handling IC Size	2x2 mm ~ 50x50 mm
Etchant	Fuming Nitric Acid, Sulfuric Acid, Fuming Sulfuric Acid
Cleaning System	Acetone
Heating Temperature	1. Beam Heater : (Room Temp.)~ 400 °C 2. Jig Heater : (Room Temp.)~ 250 °C Free Control by Dual Heating System
Process Time	Etching~Cleaning: 3~15 min. (Average Time)
Utility	Roted Voltage : AC 220V, 1 Phase Roted Current : 15A Roted Frequency : 50 ~ 60 Hz Air Pressure : 6kg/cm <sup>2</sup> (bar) Fume Exhaust Line De-Ionized Water Supply / Drain
Program	Microprocessor Control Panel

